

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION: Duck Kyun CHOI

GROUP ART UNIT: 2823

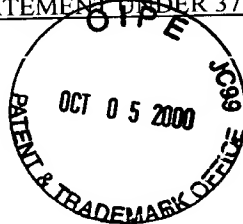
SERIAL NUMBER: 09/170,625

EXAMINER: S. Hawranek

FILED: October 13, 1998

FOR: METHOD FOR FABRICATING A THIN FILM TRANSISTOR

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. 1.97

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Applicant(s) wish to disclose the following information.

REFERENCES

- The Applicant(s) wish to make of record the references listed on the attached Form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.

- A check is attached in the amount required under 37 CFR § 1.17(p).

RELATED CASES

- Attached is a list of applicant's pending applications or issued patents which may be related to the present application. A copy of the patent(s) is attached along with PTO 1449.

- A check is attached in the amount required under 37 CFR § 1.17(p).

CERTIFICATION

The undersigned certifies that

- each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- no item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this statement.

PETITION

- Applicant(s) hereby request consideration of the attached information. A check is attached in the amount of the Petition fee required under 37 CFR § 1.17(i)(1).

DEPOSIT ACCOUNT

- Please charge any additional fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit account No. 50-0911. A duplicate copy of this sheet is enclosed.

10/06/2000 SSITHIB1 00000030 09170625

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240.00 OP

Respectfully submitted,

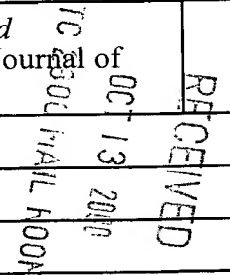
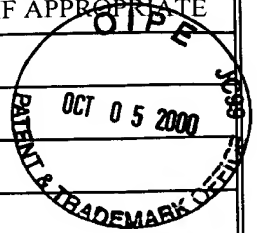
LONG, ALDRIDGE & NORMAN LLP

Date:

October 5, 2000Rebecca A. Goldman
Attorney of Record
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Washington, D.C. 20004
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Facsimile No: (202) 624-1298RECEIVED
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Form PTO 1449 (Modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO.: 8733.6836		SERIAL NO.: 09/170,625		
LIST OF REFERENCES CITED BY APPLICANT (Use Several Sheets if Necessary)		APPLICANT: Duck Hyun CHOI				
		FILING DATE: October 13, 1998		GROUP: 2823		
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	4,309,225	FAN et al.	148	1.5	
	AB	4,626,448	HAYS	427	39	
	AC	5,364,664	TSUBOUCHI et al.	427	535	
	AD	5,492,843	ADACHI et al.	437	21	
	AE	5,576,222	ARAI et al.	437	4	
	AF	5,619,044	MAKITA et al.	257	64	
	AG	5,639,698	YAMAZAKI et al.	437	228	
	AH	5,663,077	ADACHI et al.	438	151	
	AI	5,677,240	MURIKAMI et al.	437	195	
	AJ	5,985,741	YAMAZAKI et al.	438	486	
	AK	6,066,547	MAEKAWA	438	486	
	AL					
	AM					
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AN	21-40915	JP (Japan)	Abstract		
	AO	80-06053	JP (Japan)	Abstract		
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)						
	AP	Y. Kawazu, et al., "Low-Temperature Crystallization of Hydrogenated Amorphous Silicon Induced by Nickel Silicide Formation", Japanese Journal of Applied Phys., Vol. 29, No. 12, December 1990, pp. 2698-2704				
	AQ					
	AR					
	AS					
EXAMINER:		DATE CONSIDERED:		<div style="text-align: center;"> RECEIVED OCT 13 2000 PATENT & TRADEMARK OFFICE </div>		
*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						

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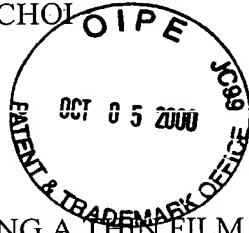
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RELATED CASES STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Applicant hereby provides a list of pending U.S. applications or issued patents which may be related to the present application.

<u>Examiner's Initial</u>	<u>U.S. Serial Number</u>	<u>Filing Date</u>	<u>Inventor Name</u>	<u>Our Ref.</u>
_____	09/115,498	04/14/98	JANG et al.	8733.6584
_____	09/299,571	04/27/99	JANG et al.	8733.8205
_____	09/350,816	04/09/99	JANG et al.	8733.20020


Date Considered: _____

Respectfully submitted,

LONG, ALDRIDGE & NORMAN LLP

October 5, 2000

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